

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re New Patent Application of )  
Yoshiaki HASEGAWA et al. )  
Japanese Priority Application No. 2000-360615 ) Attn: Applications  
Japanese Priority Date: November 28, 2000 ) Branch  
For: METHOD FOR MANUFACTURING )  
SEMICONDUCTOR AND METHOD FOR )  
MANUFACTURING SEMICONDUCTOR )  
DEVICE ) Date: November 26, 2001

*[Signature]*  
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7-15-02  
JCE21 U.S. PTO  
09/993771  
11/27/01

INFORMATION DISCLOSURE STATEMENT

Honorable Commissioner for Patents and Trademarks  
Washington, D.C. 20231

Sir:

In accordance with the provisions of 37 C.F.R. 1.56 and 37 C.F.R. 1.97-1.99, it is requested that the references listed on the attached Form PTO-1449 be made of record in the above-identified application.

Copies of these references are submitted herewith in accordance with 37 C.F.R. 1.98(a).

Respectfully submitted,

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